

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Masaharu Nagai et al. Art Unit : 1756  
Serial No. : 10/694,986 Examiner : Daborah Chacko Davis  
Filed : October 29, 2003 Conf. No. : 5334  
Title : METHOD FOR REMOVING RESIST PATTERN AND METHOD FOR  
MANUFACTURING SEMICONDUCTOR DEVICE

MAIL STOP AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**REPLY TO ACTION OF APRIL 5, 2007**

Please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 8 of this paper.